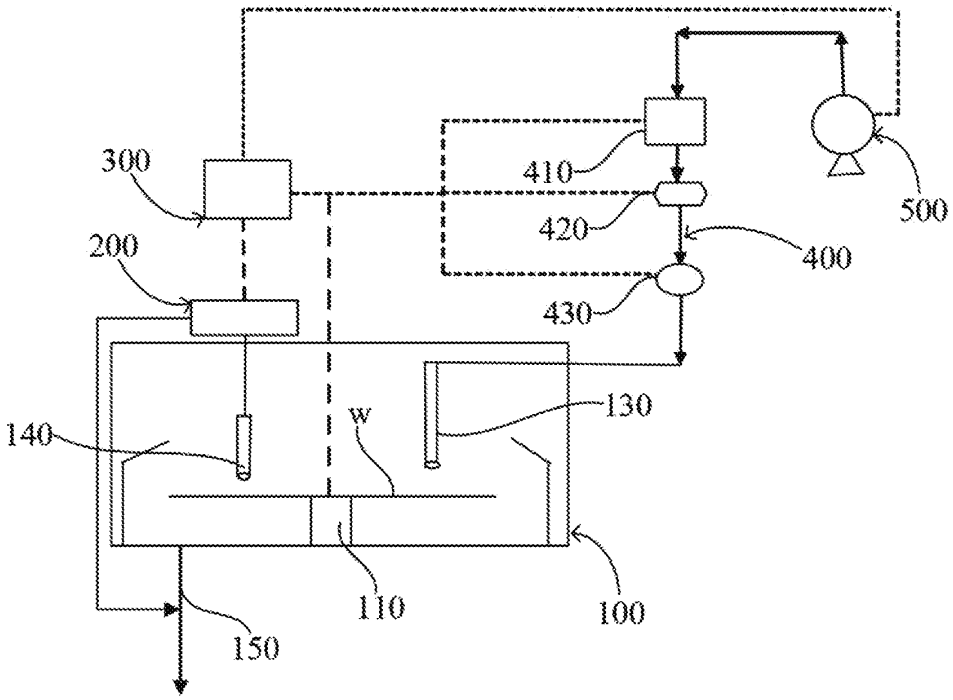


图 1

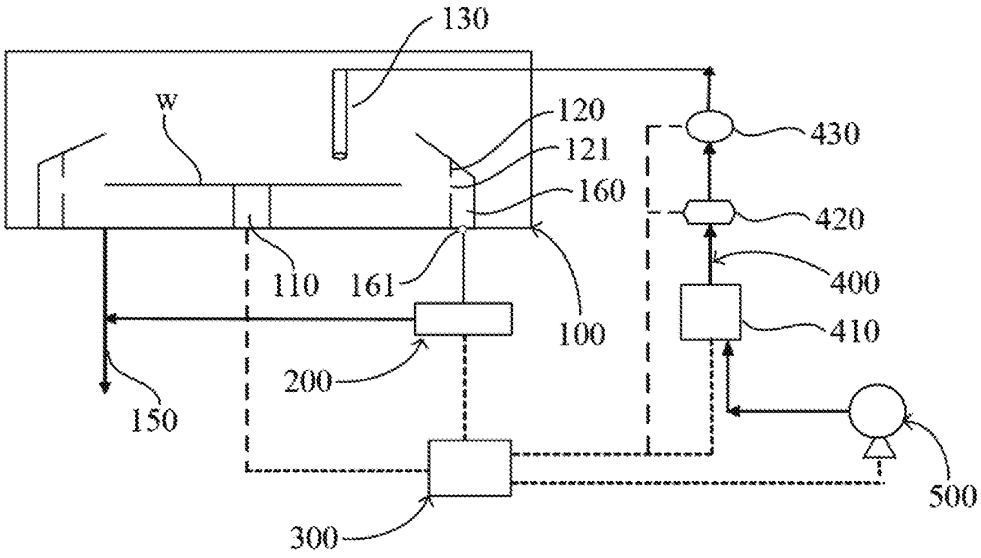


图 2

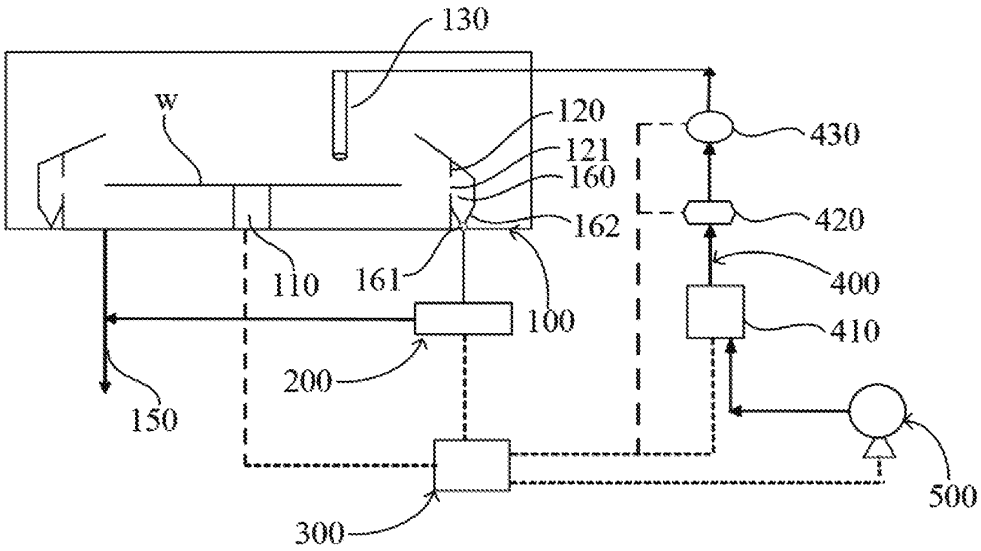


图 3

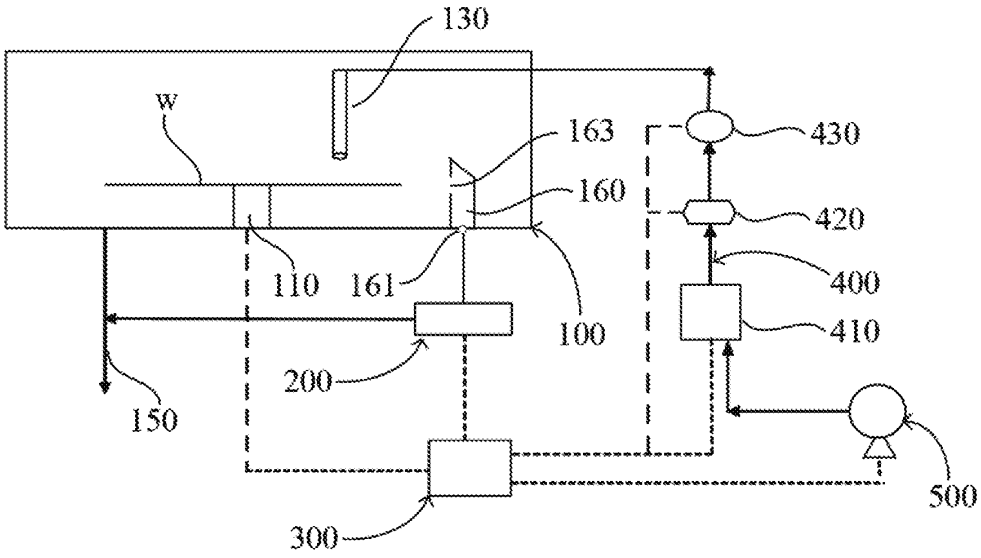


图 4

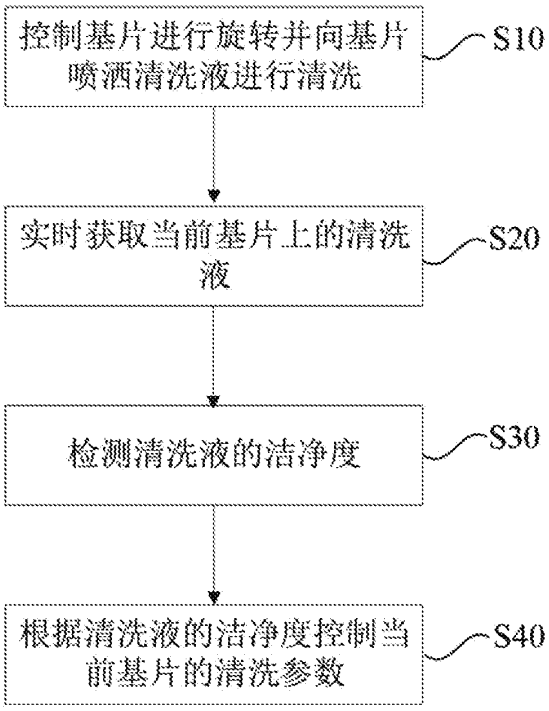

控制基片进行旋转并向基片喷洒清洗液进行清洗
S10
实时获取当前基片上的清洗液
S20
检测清洗液的洁净度
S30
根据清洗液的洁净度控制当前基片的清洗参数
S40

图 5